

OK TO ENTER: /D.N.W./

Docket No.: 17452/017001
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Provisional Application of:
Bertrand Vielleroche, et al.

Application No.: 10/539,572

Confirmation No.: 4337

Filed: June 17, 2005

Art Unit: 2621

For: PARALLEL CONFOCAL LASER
MICROSCOPY SYSTEM BASED ON VCSEL
TECHNOLOGY

Examiner: David N. Werner

REPLY UNDER 37 C.F.R. § 1.116

MS AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

OK TO ENTER: /D.N.W./

Dear Sir:

In response to the Final Office Action dated February 4, 2010, please reconsider this application in view of the following:

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